

IN THE
UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): Osamu Samuel Nakagawa

Confirmation No.: 7685

Application No.: 10/690,730

Examiner: Schillinger, Laura

Filing Date: Oct. 22, 2003

Group Art Unit: 2813

Title: PROCESS FOR HIGH-DIELECTRIC CONSTANT METAL-INSULATOR METAL CAPACITOR
IN VLSI MULTI-LEVEL METALLIZATION SYSTEMS

Mail Stop Amendment
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL LETTER FOR RESPONSE/AMENDMENT

Sir:

Transmitted herewith is/are the following in the above-identified application:

- (X) Response/Amendment () Petition to extend time to respond
() New fee as calculated below () Supplemental Declaration
(X) No additional fee
() Other: (fee \$)

CLAIMS AS AMENDED BY OTHER THAN A SMALL ENTITY						
(1) FOR	(2) CLAIMS REMAINING AFTER AMENDMENT	(3) NUMBER EXTRA	(4) HIGHEST NUMBER PREVIOUSLY PAID FOR	(5) PRESENT EXTRA	(6) RATE	(7) ADDITIONAL FEES
TOTAL CLAIMS	14	MINUS	20	= 0	X \$50	\$ 0
INDEP. CLAIMS	3	MINUS	3	= 0	X \$200	\$ 0
[] FIRST PRESENTATION OF A MULTIPLE DEPENDENT CLAIM					+ \$360	\$ 0
EXTENSION FEE	1ST MONTH \$120.00	2ND MONTH \$450.00	3RD MONTH \$1020.00	4TH MONTH \$1590.00		\$ 0
OTHER FEES						\$
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$ 0

Charge \$ 0 to Deposit Account 08-2025. At any time during the pendency of this application, please charge any fees required or credit any overpayment to Deposit Account 08-2025 pursuant to 37 CFR 1.25. Additionally please charge any fees to Deposit Account 08-2025 under 37 CFR 1.16 through 1.21 inclusive, and any other sections in Title 37 of the Code of Federal Regulations that may regulate fees. A duplicate copy of this sheet is enclosed.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450.

Date of Deposit: March 11, 2005

Typed Name: Judy H. Chung

Signature: 

Respectfully submitted,

Osamu Samuel Nakagawa

By 

Timothy B. Kang

Attorney/Agent for Applicant(s)

Reg. No. 46,423

Date: March 11, 2005

DFW

PATENT
Atty Docket No.: 10004808-2



In The United States Patent and Trademark Office

Applicant(s): Osamu Samuel Nakagawa **Confirmation No.:** 7685
U.S. Serial No.: 10/690,730 **Examiner:** Laura M. Schillinger
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METAL CAPACITOR IN VLSI MULTI-LEVEL METALLIZATION SYSTEMS

MAIL STOP AMENDMENT

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CERTIFICATE OF MAILING WITH THE USPTO

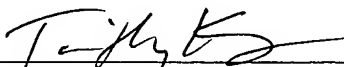
I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313-1450. This correspondence contains the following document(s):

1 sheet of Transmittal Letter for Response/Amendment. (2 copies).
12 sheets of Amendment Under 37 C.F.R. § 1.111.

Respectfully submitted,

MANNAVA & KANG, P.C.

Date of Deposit:
March 11, 2005

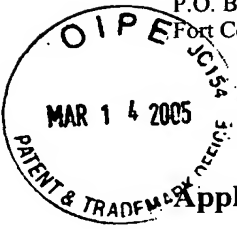


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Atty Docket No. 10004808-2



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AMENDMENT UNDER 37 C.F.R. § 1.111

Sir:

Applicants respectfully submit this Amendment in response to the Official Action mailed on December 14, 2004. The Examiner is respectfully requested to consider the remarks following the listing of the pending claims.